

* NOTICES *

JPO and INPIT are not responsible for any damages caused by the use of this translation.

- 1.This document has been translated by computer. So the translation may not reflect the original precisely.
- 2.**** shows the word which can not be translated.
- 3.In the drawings, any words are not translated.

DESCRIPTION OF DRAWINGS

[Brief Description of the Drawings]

[Drawing 1]It is a perspective view showing the simulated defect sample of this invention, and the laser marking device which records a simulated defect.

[Drawing 2]It is a schematic diagram showing a defect inspection device.

[Drawing 3]It is a front view showing the simulated defect sample arranged to the scanning position.

[Drawing 4]It is an explanatory view showing the diffusion degree of the optical beam in the simulated defect of this invention.

[Drawing 5]It is an explanatory view showing the diffusion degree of the laser beam at the time of making the scanning direction of a laser beam, and a simulated defect cross at right angles, and constituting it.

[Drawing 6]It is a front view showing the simulated defect sample which has a simulated defect of several different classification.

[Drawing 7]It is a front view in which changing an angle of gradient into for the same simulated defect, and showing the poor simulated defect sample about the same as plurality.

[Drawing 8]It is a front view in which changing an angle of gradient into for the simulated defect of a different classification, and showing the poor simulated defect sample about the same as plurality.

[Description of Notations]

10, 65, 70, and 80 Simulated defect sample

12 Laser marking device

13, 60-64, 71-74, 75-78 Simulated defect

20 Defect inspection device

30 Photodetector

31 Mask

32 Sensor window

[Translation done.]